

Docket No.: 50432-096

SADH
#2
4-8-02
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Calvin T. GABRIEL, et al.

Serial No.: 09/887,165

Filed: June 25, 2001

Group Art Unit: 1746

Examiner: *OLSEN*

RECEIVED

SEP 28 2001

TC 1700

For: **N-CONTAINING PLASMA ETCH PROCESS WITH REDUCED RESIST
POISONING**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Each reference cited is in the English language.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

A handwritten signature in cursive script, appearing to read "Matthew V. Grumbling".

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